

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Basol et al.
App. No : 10/782,697
Filed : February 18, 2004
For : METHOD OF WAFER PROCESSING
WITH EDGE SEED LAYER
REMOVAL
Examiner : Michael Manh Trinh
Art Unit : 2822
Conf. No. : 5582

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March 6, 2008

(Date)

Adam Gilbert, Reg. No. 59,967**RESPONSE TO OFFICE ACTION DATED DECEMBER 17, 2007****Mail Stop Amendment**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated December 17, 2007, the Applicants respectfully request that the Examiner reconsider the above-identified patent application in view of the following remarks.

Listing of the Claims begins on page 2 of this paper.

Remarks begin on page 5 of this paper.